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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yi-Nien Su

Group Art Unit: 1765

Serial No.: 10/077,720

Examiner: Anita Karen Alanko

Filed: 02/15/2002

In Response to Office Action
Dated: March 23, 2004

For: A METHOD FOR IMPROVED PLASMA ETCHING CONTROL

Attorney Docket No.: 67,200-478

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Date: June 23, 2004

Kathy Dixon

REQUEST FOR RECONSIDERATION

Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to a final Office Action mailed March 23, 2004, please enter the following amendments and consider the following remarks.